



520.39581X00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant(s): T. USUI, et al

Serial No.: 09/788,629

Filed: February 16, 2001

For: PROCESS MONITORING METHODS IN A PLASMA
PROCESSING APPARATUS, MONITORING UNITS, AND A
SAMPLE PROCESSING METHOD USING THE MONITORING
UNITS

Group: 1763

Examiner: G. Goudreau

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AMENDMENT

Mail Stop
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

November 28, 2003

Sir:

In response to the Office Action August 28, 2003, the following amendments and remarks are respectfully submitted in connection with the above-identified application, as listed below and as set forth on the following pages:

Amendment of the Claims; and

Remarks are included following the amendments.

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